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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

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Tohru SASAKI and Toshihiro FUJII

Application No.: New US Patent Application

Filed: June 1, 2001

Docket No.: 109675

For: METHOD AND APPARATUS FOR ION ATTACHMENT MASS SPECTROMETRY

PRELIMINARY AMENDMENT

Director of the U.S. Patent and Trademark Office
Washington, D. C. 20231

Sir:

Prior to initial examination, please amend the above-identified application as follows:

Please replace claims 3, 4, 8 and 12 as follows:

3. (Amended) A method of ion attachment mass spectrometry as set forth in claim 1, wherein a quantitative value is calculated for said each component using sensitivity corresponding to the total pressure during measurement.

4. (Amended) A method of ion attachment mass spectrometry as set forth in claim 1, wherein the total pressure during the measurement is set within an allowable fluctuation of total pressure.

8. (Amended) An apparatus for ion attachment mass spectrometry as set forth in claim 6, further provided between said reaction chamber and said analysis chamber with a differential evacuation chamber of a reduced pressure atmosphere for connecting said two chambers in a vacuum state.

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12 (Amended) An apparatus for ion attachment mass spectrometry as set forth in claim 10, wherein

the allowable fluctuation of total pressure is calculated from a rate of change of sensitivity corresponding to the total pressure of said reduced pressure atmosphere during the measurement and a required quantitative error value.

Please add new claims 13-16 as follows:

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--13. A method of ion attachment mass spectrometry as set forth in claim 2, wherein a quantitative value is calculated for said each component using sensitivity corresponding to the total pressure during measurement.--

--14. A method of ion attachment mass spectrometry as set forth in claim 2, wherein the total pressure during the measurement is set within an allowable fluctuation of total pressure.--

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--15. An apparatus for ion attachment mass spectrometry as set forth in claim 7, further provided between said reaction chamber and said analysis chamber with a differential evacuation chamber of a reduced pressure atmosphere for connecting said two chambers in a vacuum state.--

--16. An apparatus for ion attachment mass spectrometry as set forth in claim 11, wherein

the allowable fluctuation of total pressure is calculated from a rate of change of sensitivity corresponding to the total pressure of said reduced pressure atmosphere during the measurement and a required quantitative error value.--

REMARKS

Claims 1-16 are pending. Claims 3, 4, 8 and 12 are amended to eliminate multiple dependencies and claims 13-16 are added to compensate for subject matter deleted from